

ABSTRACT OF THE DISCLOSURE

The present invention provides a thin magnetoelectric transducer which has a projected size substantially equal
5 to that of a pellet and which can be subjected to an inspection test nondestructively. The magnetoelectric transducer has a semiconductor device provided on the upper surface of a projecting portion of a projecting non-magnetic insulating substrate 9 and comprising a
10 magnetosensitive section 3 and inner electrodes 2 made of metal. A conductive resin layer 4 is formed on the internal electrodes 2 and on part of the side surfaces of the projecting portion. A strain buffering layer 5 is formed at least on the magnetosensitive section 3. Furthermore,
15 at least the strain buffering layer 5 on the magnetosensitive section 3 is coated with a protective layer 6.